

## **LISTING OF THE CLAIMS**

This listing of claims will replace all prior versions, and listings, of claims in the application:

### **Claims 1-8 (Canceled)**

### **Claim 9 (Currently Amended)**

A substrate treating apparatus for performing a predetermined treatment of a plurality of substrates as immersed in a heated treating solution, comprising:

a treating tank for storing the heated treating solution;  
a substrate transport mechanism for transporting the plurality of substrates;  
a substrate holding device for holding the substrates received from said substrate transport mechanism and immersing the substrates in the heated the treating solution stored in said treating tank; and

control part a controller which keeps for keeping said substrate holding device on standby in the heated treating solution stored in said treating tank to preheat said substrate holding device, and when the plurality of substrates are transported by said substrate transport mechanism to said treating tank, raises said substrate holding device from said treating tank to receive the plurality of substrates from said substrate transport mechanism, and lowers said substrate holding device having received the plurality of substrates to immerse the substrates in the heated treating solution in the treating tank, thereby to treat the substrates, before said substrate holding device receives the substrates from said substrate transport mechanism.

### **Claim 10 (Original)**

A substrate treating apparatus as defined in claim 9, wherein said heated treating solution is a phosphoric acid solution.

**Claim 11 (Original)**

A substrate treating apparatus as defined in claim 9, wherein said heated treating solution is sulfuric acid.

**Claim 12 (Original)**

A substrate treating apparatus as defined in claim 9, wherein said predetermined treatment of said substrates as immersed in said heated treating solution is etching treatment.

**Claim 13 (Currently Amended)**

A substrate treating apparatus for performing a predetermined treatment of a plurality of substrates as immersed in a heated treating solution, comprising:

a treating tank for storing the heated treating solution;  
a substrate transport mechanism for transporting the plurality of substrates; and  
a substrate holding device for holding the substrates received from said substrate  
transport mechanism and immersing the substrates in the heated ~~the~~ treating solution stored  
in said treating tank; and

a controller which controls the treatment of the substrates by immersing said  
substrate holding device holding the substrates in the heated treating solution stored in said  
treating tank;

wherein said substrate holding device includes a plurality of holding rods for holding  
the plurality of substrates in vertical posture, and a back plate supporting said holding rods  
in cantilever fashion, said back plate having a heating device; and

said controller further preheats said back plate by means of said heating device  
before the treatment of the substrates.

**Claim 14 (Original)**

A substrate treating apparatus as defined in claim 13, wherein said heated treating solution is a phosphoric acid solution.

**Claim 15 (Original)**

A substrate treating apparatus as defined in claim 13, wherein said heated treating solution is sulfuric acid.

**Claim 16 (Original)**

A substrate treating apparatus as defined in claim 13, wherein said predetermined treatment of said substrates as immersed in said heated treating solution is etching treatment.